



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/388,826  
Filing Date ..... September 1, 1999  
Inventor ..... Weimin (Michael) Li et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... E. Kielin  
Attorney's Docket No. .... MI22-1208  
Title: Low k Interlevel Dielectric Layer Fabrication Methods

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References –See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: 16 Sep 2003

By: 

James E. Lake  
Reg. No. 44,854

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1208	SERIAL NO. 09/388,826	
<div style="position: relative; height: 100px;"> <div style="position: absolute; top: 0; left: 0; width: 100%; height: 100%; border: 2px solid black; border-radius: 50%; text-align: center; font-size: 24px; line-height: 1;">             OIPE SEP 16 2003 PATENT &amp; TRADEMARK OFFICE           </div> </div>				LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		
				APPLICANT Weimin Li, et al.		
				FILING DATE September 1, 1999	GROUP 2813	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6518122	02/2003	Chan et al		
	AB	6492688	12/2002	Ilg		
	AC	6373114	04/2002	Jeng et al		
	AD	2001/0019868	09/2001	Gonzalez et al		
	AE	2001/0003064	06/2001	Ohto		
	AF	2003/0013311	01/2003	Chang et al		
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes    No
	AM					
	AN					
	AO					
	AP					
	AQ					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						

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